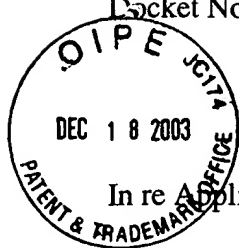


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1-30-04

Docket No.: 005198 USA/Consilium/Consilium

PATENT/OFFICIAL



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of

Parris C.M. HAWKINS et al.

Serial No. 09/800,980

Filed: March 8, 2001

For: DYNAMIC AND EXTENSIBLE TASK GUIDE

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: Group Art Unit: 2121  
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: Examiner:

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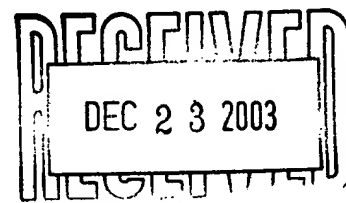
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**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

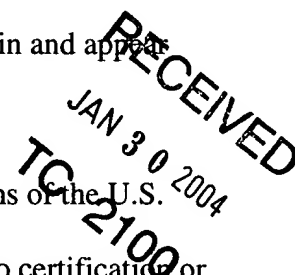
Honorable Commissioner for Patents  
Alexandria, VA 22313-1450

Sir:



In accordance with the provisions of 37 C.F.R. 1.56, 1.97 and 1.98, the attention of the Patent and Trademark Office is hereby directed to the documents listed on the attached form PTO-1449. It is respectfully requested that the documents be expressly considered during the prosecution of this application, and that the documents be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required.



This submission does not constitute a representation that a search has been made or that no better art exists and does not constitute an admission or representation that any of the listed documents is material or constitutes prior art. If it should be determined that any of the listed documents does not constitute prior art under the United States law, Applicants reserve the right

**Serial No. 09/800,980**

to present to the Office the relevant facts and law regarding the appropriate status of such document.

No certification or fee is believed to be required. However, the Commissioner is hereby authorized to charge any additional fees should any be required for this submission, or credit any overpayment to deposit account no. 08-0219.

Respectfully submitted,

HALE AND DORR LLP



Scott M. Alter

Registration No. 32,879

Reston Town Center  
11951 Freedom Drive  
Reston, VA 20190  
TEL (703) 654-7021 SMA/mgm  
FAX (703) 654-7100  
Date: 12/16/03

**INFORMATION DISCLOSURE  
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(PTO-1449)**

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Parris C.M. HAWKINS et al.

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FILING DATE  
March 8, 2001

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**U.S. PATENT DOCUMENTS**

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						Yes	No
	WO 01/11679	02/15/01	WIPO			X	
	WO 01/080306	10/25/01	WIPO			X	

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	Miller, G. L., D. A. H. Robinson, and J. D. Wiley. July 1976. "Contactless measurement of semiconductor conductivity by radio frequency-free-carrier power absorption." <i>Rev. Sci. Instrum.</i> , Volume 47, No. 7. pp. 799 - 805.
	1999. "Contactless Bulk Resistivity/Sheet Resistance Measurement and Mapping Systems." <a href="http://www.Lehighton.com/fabtech1/index.html">www.Lehighton.com/fabtech1/index.html</a> .
	2000. "Microsense II Capacitance Gaging System." <a href="http://www.adetech.com">www.adetech.com</a> .

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.



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	El Chemali, Chadi et al. July/August 2000. "Multizone uniformity control of a chemical mechanical polishing process utilizing a pre- and postmeasurement strategy." <i>J. Vac. Sci. Technol.</i> Volume 18, No. 4. pp. 1287 – 1296.
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